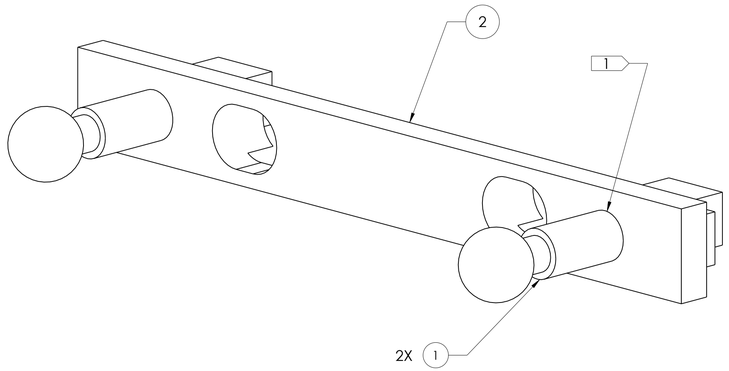
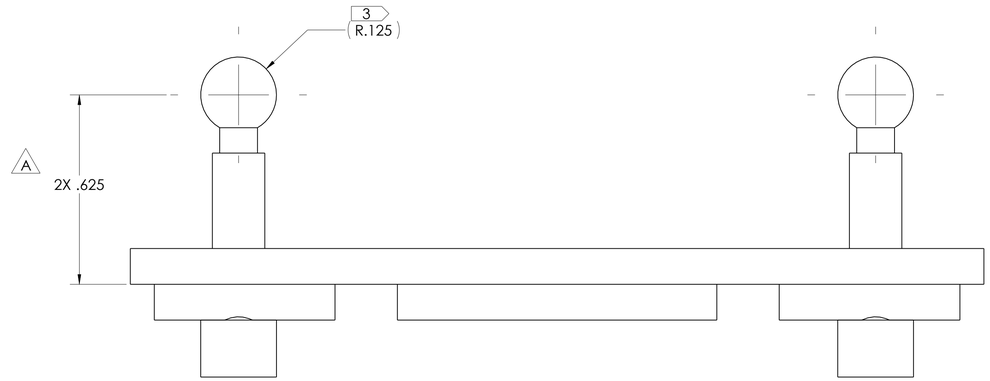
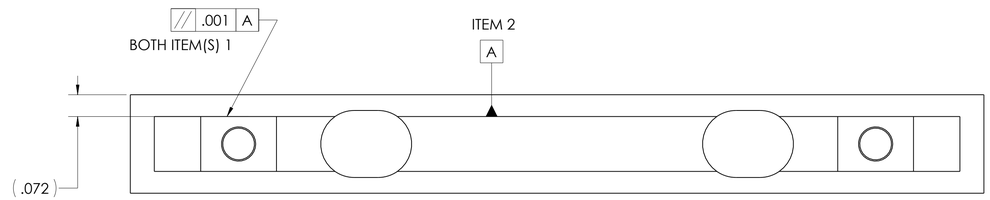
DWG. NO.	SIZE	REV.	SH.
nnXnnn4	A	A	1

DESCRIPTION	MATERIAL	MAT. LOCATION







REAR VIEW

1 STAVE END CLOSEOUT #1
QTY #1

NOTES:

1. PRESS FIT ITEM(S) 1 INTO ITEM 2. INTERFERENCE SHOULD BE 0.0000/0.0004".
2. DIMENSIONS ARE IN INCHES.
3. TOOLING BALL PART NO. 224-4, INDUSTRIAL TECTONICS INC.

ITEM NO	SHEET LOCATION	ZONE	QTY REQ'D PER ASSY A3	A2	A1	PART DOCUMENT NUMBER	DESCRIPTION
3	2	C5		1			END CLOSEOUT #2
2	1	C5			1		END CLOSEOUT #1
1	MULT	MULT		2	2		CLOSEOUT PIN

REV	DWG	CHK	ZONE	DATE	CHANGES
A				11-24-06	ADDED VIEWS, TOOLING BALLS

UNLESS OTHERWISE SPECIFIED
TOLERANCES: X.X ± 0.1 | FRAC. ± 1/64 | X.XX ± 0.01 | ANGLES ± 30' | X.XXX ± 0.005 | FINISH -
DO NOT SCALE PRINT
THREADS ARE CLASS 2
CHAMFER ENDS OF ALL SCREW THREADS 30 °
CUT ROUND, 1.5 THREAD RELIEF ON MACHINED THREADS
BREAK EDGES .016 MAX. ON MACHINED WORK
REMOVE BURRS, WELD SPLATTER & LOOSE SCALE
IN ACCORDANCE WITH ASME Y14.5m & B46.1

SHOP ORDERS
ACCT NO. | NO. REQD | SER NO.
DEL TO | DATE ISSD
SURFACE TREATMENT | DATE REQD
IDEN METHOD TAG
PROJECT NUMBER ATL-IP-ED-XXXX
US ATLAS SILICON SUBSYSTEM

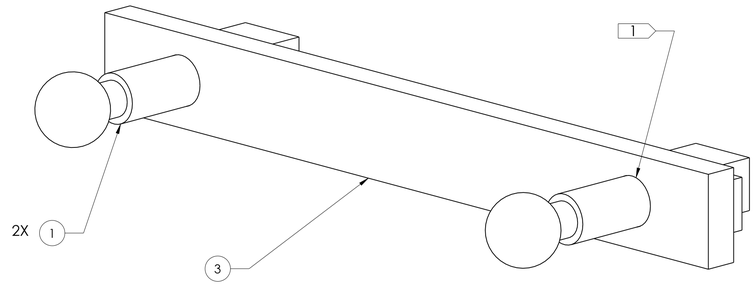
ERNEST ORLANDO LAWRENCE BERKELEY NATIONAL LABORATORY
UNIVERSITY OF CALIFORNIA - BERKELEY

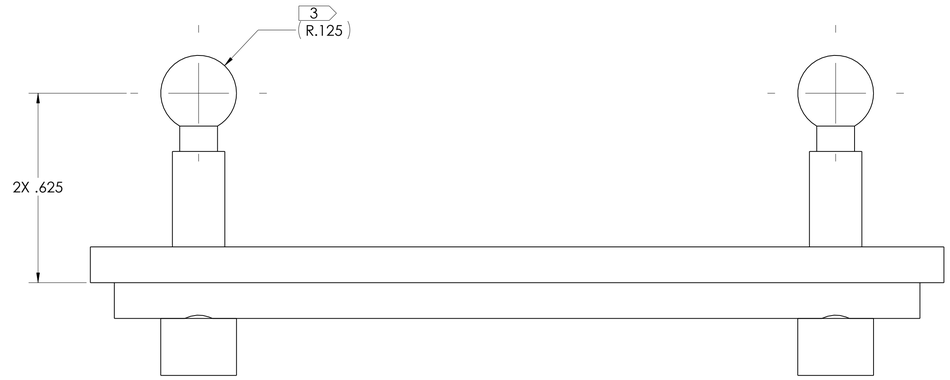
1m STAVE
STAVE END SUB ASSEBMLY
(12cm WAFER)

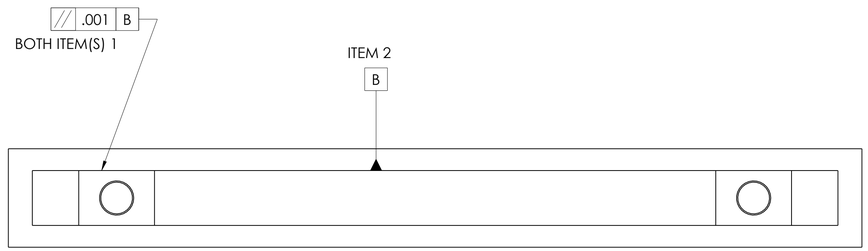
PROJECT NAME	MICROFILMED:	DWG. TYPE	SHOWN ON	SCALE:	DO NOT SCALE PRINTS
US ATLAS SILICONE SUBSYSTEM		PART	nnXnnn	4:1	

DWG BY	DATE	PATENT CLEAR:	DESIGN ACCT. NO.	CATEGORY CIDE	DWG. NO.	SIZE	REV.
W. K. MILLER	7/6/2006		P1AP-11	AP6250	nnXnnn4	A	A
CHK BY W. O. MILLER	7/6/2006						
APR BY -	DATE -						

SHEET 1 OF 2







REAR VIEW

2 STAVE END CLOSEOUT #2
QTY #1

UNLESS OTHERWISE SPECIFIED

TOLERANCES:
X.X ± 0.1 | FRAC. ± 1/64
X.XX ± 0.01 | ANGLES ± 30'
X.XXX ± 0.005 | FINISH -

DO NOT SCALE PRINT

THREADS ARE CLASS 2
CHAMFER ENDS OF ALL SCREW THREADS 30 °
CUT ROUND, 1.5 THREAD RELIEF ON MACHINED THREADS
BREAK EDGES .016 MAX. ON MACHINED WORK
REMOVE BURRS, WELD SPLATTER & LOOSE SCALE
IN ACCORDANCE WITH ASME Y14.5m & B46.1

SHOP ORDERS

ACCT NO. | NO. REQD
DEL TO
SURFACE TREATMENT
IDEN METHOD TAG
PROJECT NUMBER ATL-IP-ED-XXXX
PROJECT NAME US ATLAS SILICONE SUBSYSTEM
DWG BY W. K. MILLER | DATE 7/6/2006
CHK BY W. O. MILLER | DATE 7/6/2006
APR BY - | DATE -

SER NO.
DATE ISSD
DATE REQD
US ATLAS SILICON SUBSYSTEM (USSS)

ERNEST ORLANDO LAWRENCE
BERKELEY NATIONAL LABORATORY
UNIVERSITY OF CALIFORNIA - BERKELEY

1m STAVE
STAVE END SUB ASSEBMLY
(12cm WAFER)

MICROFILMED:
PATENT CLEAR:
DWG. TYPE: PART
SHOWN ON: nnXnnn
SCALE: 4:1
DO NOT SCALE PRINTS
SHEET 2 OF 2
DESIGN ACCT. NO.: P1AP-11
CATEGORY CIDE: AP6250
DWG. NO.: nnXnnn4
SIZE
REV.: A